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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
Yoshihiro MORI et al.) Group Art Unit: 2813
Serial No. 09/942,038) Examiner: Yen-nhu B. HUYNH
Filed: August 30, 2001)
For: CAPACITOR AND METHOD FOR)
FABRICATING SEMICONDUCTOR)
(To Be Amended))

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02 FC:1202

288.00 OP

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Examiner's Office Action mailed July 1, 2002, the due date for which having been extended one month (1) to November 1, 2002, please consider the following amendments and remarks in connection with the above-identified application.

IN THE TITLE: ✓

Please delete the title of the invention in its entirety and substitute therefore the following new title: --A METHOD FOR FABRICATING SEMICONDUCTOR DEVICE INCLUDING ANNEALING AN ELECTRODE IN A REDUCING ATMOSPHERE--.

IN THE CLAIMS: ✓

Please cancel claim 10 without prejudice or disclaimer to the subject matter disclosed therein.

Please amend claims 11 and 12 as follows:

11. (Amended) A method for fabricating a semiconductor device that includes, as a component thereof, an electrode made of a noble metal or a refractory metal, the method comprising the steps of:

- a) forming the electrode;
- b) annealing the electrode in a reducing atmosphere; and

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